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APPLICATION NO.	FIL	ING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.	
10/651,855	08	3/29/2003	Shuichi Kikuchi	10417-057002	9444	
26211	7590	11/24/2004		EXAMINER		
FISH & RI	011111111111111111111111111111111111111	ON P.C. 52ND FLOOR	NGUYEN, THANH T			
153 EAST 5				ART UNIT	PAPER NUMBER	
NEW YORK	K, NY 100	022-4611		2813		
				DATE MAIL ED: 11/24/200	4	

Please find below and/or attached an Office communication concerning this application or proceeding.

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•	Application No.	Applicant(s)	· ·				
Office Action Commence	10/651,855	KIKUCHI ET AL.					
Office Action Summary	Examiner	Art Unit					
	Thanh T. Nguyen	2813	<u>:</u>				
The MAILING DATE of this communication apperiod for Reply	opears on the cover sheet with the	ne correspondence add	ress				
A SHORTENED STATUTORY PERIOD FOR REPI THE MAILING DATE OF THIS COMMUNICATION - Extensions of time may be available under the provisions of 37 CFR 1 after SIX (6) MONTHS from the mailing date of this communication. - If the period for reply specified above is less than thirty (30) days, a regilif NO period for reply is specified above, the maximum statutory period - Failure to reply within the set or extended period for reply will, by statu Any reply received by the Office later than three months after the mailing earned patent term adjustment. See 37 CFR 1.704(b).	 .136(a). In no event, however, may a reply b ply within the statutory minimum of thirty (30 d will apply and will expire SIX (6) MONTHS te, cause the application to become ABAND	be timely filed days will be considered timely. from the mailing date of this com ONED (35 U.S.C. § 133).	munication.				
Status		•					
1) Responsive to communication(s) filed on	<u></u> .		:				
2a)☐ This action is FINAL . 2b)☑ Th	is action is non-final.		•				
3) Since this application is in condition for allow	3) Since this application is in condition for allowance except for formal matters, prosecution as to the merits is						
closed in accordance with the practice under Ex parte Quayle, 1935 C.D. 11, 453 O.G. 213.							
Disposition of Claims			:				
4)⊠ Claim(s) <u>1-3 and 7-10</u> is/are pending in the a	nnlication		• •				
4a) Of the above claim(s) is/are withdra			:				
5) Claim(s) is/are allowed.			:				
6) Claim(s) 1-3 and 7-10 is/are rejected.			:				
7) Claim(s) is/are objected to.							
8) Claim(s) are subject to restriction and/	or election requirement.		:				
Application Papers							
9)☐ The specification is objected to by the Examir	ner		-				
10) The drawing(s) filed on is/are: a) accepted or b) objected to by the Examiner.							
Applicant may not request that any objection to the	, , , , , , , , , , , , , , , , , , , ,		i				
Replacement drawing sheet(s) including the corre			: R 1.121(d).				
11) The oath or declaration is objected to by the E			•				
Priority under 35 U.S.C. § 119			<u>:</u> :				
		0(-) (-) (0	: :				
 12) Acknowledgment is made of a claim for foreig a) All b) Some * c) None of: 1. Certified copies of the priority documer 2. Certified copies of the priority documer 3. Copies of the certified copies of the priority 	nts have been received. nts have been received in Appli	cation No	tage				
application from the International Bure	au (PCT Rule 17.2(a)).						
* See the attached detailed Office action for a list	st of the certified copies not rec	eived.	•				
			:				
	•		•				
Attachment(s)		(878.445)	1				
1) Notice of References Cited (PTO-892) 2) Notice of Draftsperson's Patent Drawing Review (PTO-948)	4) Ll Interview Sumr Paper No(s)/Ma	nary (PTO-413) ail Date	:				
3) Information Disclosure Statement(s) (PTO-1449 or PTO/SB/08 Paper No(s)/Mail Date 8/29/03.		nal Patent Application (PTO-	152)				
			:				

DETAILED ACTION

Priority

Acknowledgment is made of applicant's claim for foreign priority under 35 U.S.C. 119

(a)-(d). The certified copy has been filed in parent Application No. 09/789,163, filed on 2/20/01.

Information Disclosure Statement

The information disclosure statement filed on 8/29/03 has been considered.

Oath/Declaration

Oath/Declaration filed on 8/29/03 has been considered.

Drawings

Figures 15-18 should be designated by a legend such as --Prior Art-- because only that which is old is illustrated. See MPEP § 608.02(g). A proposed drawing correction or corrected drawings are required in reply to the Office action to avoid abandonment of the application. The objection to the drawings will not be held in abeyance.

Specification

The title of the invention is not descriptive. A new title is required that is clearly indicative of the invention to which the claims are directed.

Claim Rejections - 35 USC § 102

The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:

A person shall be entitled to a patent unless -

- (b) the invention was patented or described in a printed publication in this or a foreign country or in public use or on sale in this country, more than one year prior to the date of application for patent in the United States.
- (e) the invention was described in (1) an application for patent, published under section 122(b), by another filed in the United States before the invention by the applicant for patent or (2) a patent granted on an application for patent by another filed in the United States before the invention by the applicant for patent, except that an international application filed under the treaty defined in section 351(a) shall have the effects for purposes of this subsection of an application filed in the United States only if the international application designated the United States and was published under Article 21(2) of such treaty in the English language.

Claims 1-3, 7-10 are rejected under 35 U.S.C. 102(b) as being anticipated by Vo et al. (U.S. Patent No. 5,328,859).

Referring to figures 2a-2j, Vo et al. teaches a semiconductor device comprising:

A semiconductive layer (12) of a first conductive type (n), (see figure 2h, col. 2, lines 65-67);

Forming a first gate oxide (45) and a second gate oxide (42+44) formed on the semiconductive layer;

A gate electrode (46, formed to range from the first gate oxide (44) film to the second gate oxide film (42-44);

A source region (14) of a second conductive type (p) formed adjacent to the gate electrode (46);

Drain region (20) of the second conductive type (p) formed in a position apart from the gate electrode;

Application/Control Number: 10/651,855

Art Unit: 2813

A drift region (18) of a second conductive type (p) formed so that the drift region surround the drain region, and

An impurities layer (16) of a second conductive type (p) formed adjacent to the drain region (20).

Regarding to claim 2, the impurities layer (16) is formed to range at least one end of the drain region to one end of the gate electrode (see figure 2g-2h).

Regarding to claim 3, the impurities layer (16) is formed in a surface of the drift region (18) so that it is located between one end of the drain region and one end of the gate electrode (see figure 2h).

Regarding to claim 7, referring to figures 2a-2h, Vo et al. teaches a semiconductor device comprising:

A gate electrode (46) formed on a semiconductor layer of a first conduction type (n) through a gate oxide film (44);

A highly doped source region (14, see figure 2h) of a second conduction type (p) formed to be adjacent to the gate electrode (46);

A highly doped drain region (20) of the second conduction type (p) formed at a postion apart from the gate electrode (46); and

A drift region (18) of the second conduction type (p) formed so as to surround the drain region;

Wherein an impurity region (d2, overlap region (16+18)) of the second conduction type (p) which is more lightly doped than the highly doped drain region (20) and it is more highly

Application/Control Number: 10/651,855

Art Unit: 2813

doped than the drift region (18) is formed to surround a vicinity of the highly doped drain region (see figure 2g-2h, col. 3, lines 1-30).

Regarding to claim 8, a gate oxide formed to extend from the first gate oxide film to the second gate oxide film (42+44) having a larger thickness than that of the first gate oxide film (44).

Regarding to claim 9, the impurity region (16) of the second conduction type (p) is formed to extend from at least one end of the drain region (20) and to be adjacent to one end of the gate electrode (46).

Regarding to claim 10, the impurity region (16) of the second conduction type (p) is formed evenly in depth so as to be adjacent to one end of the gate electrode (46) through the first gate oxide film and to surround the vicinity of the drain region (20).

Claim 7 is rejected under 35 U.S.C. 102(e) as being anticipated by Yang (U.S. Patent No. 6,306,711).

Regarding to claim 7, referring to figures 4a-4e, Yang et al. teaches a semiconductor device comprising:

A gate electrode (209) formed on a semiconductor layer (200) of a first conduction type (p) through a gate oxide film (208, see figure 4d, col. 2, lines 54-67);

A highly doped source region (213) of a second conduction type (n+) formed to be adjacent to the gate electrode (209, see col. 3, lines 25-34);

A highly doped drain region (212) of the second conduction type (n+) formed at a position apart from the gate electrode (209); and

Art Unit: 2813

A drift region (202) of the second conduction type (n) formed so as to surround the drain region (212);

Wherein an impurity region (203) of the second conduction type (n) which is more lightly doped than the highly doped drain region (212, n+) and it is more highly doped than the drift region (202) is formed to surround a vicinity of the highly doped drain region (see figure 4, col. 2, lines 63-65 wherein n+>n in concentration).

Conclusion

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Thanh Nguyen whose telephone number is (571) 272-1695, or by Email via address Thanh Nguyen@uspto.gov. The examiner can normally be reached on Monday-Thursday from 6:00AM to 3:30PM.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Carl Whitehead, Jr., can be reached on (571) 272-1702. The fax phone number for this Group is (703) 872-9306.

Any inquiry of a general nature or relating to the status of this application or proceeding should be directed to the Group receptionist whose telephone number is (703) 308-0956 (See MPEP 203.08).

Thanh Nguyen
Patent Examiner

Patent Examining Group 2800

TTN